

Amendments to the Abstract:

Please rewrite the Abstract as shown below:

ABSTRACT OF THE DISCLOSURE

~~There is disclosed a~~ A method is provided for manufacturing method of a
piezoelectric/electrostrictive film type device including a ceramic substrate, ~~and a~~
piezoelectric/electrostrictive operation portion ~~containing~~ including a lower electrode,
a piezoelectric/electrostrictive layer, and upper electrode stacked on the substrate, ~~and~~
~~the~~. The piezoelectric/electrostrictive layer being is formed to extend beyond at least
one of electrodes to form projected portions at its ends, ~~the~~. The method comprising
includes the steps of forming the piezoelectric/electrostrictive layer beyond at least
one of electrodes to project so that ends of the layer; piezoelectric/electrostrictive layer
are projected to extend beyond ends of at least one electrode, applying a coating liquid
in an a sufficient amount sufficient to make so that the coating liquid permeate
permeates through a gap between at least a the projected end portion of the
piezoelectric/electrostrictive layer and the substrate, and so as to coat a predetermined
portion of said ~~the~~ at least one of electrodes; electrode, and drying thus ~~the~~ applied
coating liquid to form a coupling member to couple a ~~the projected portion end~~
portions of the piezoelectric/electrostrictive layer to the substrate. The
~~piezoelectric/electrostrictive operation portion may be a multilayered structure.~~